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# United States Patent [19]

## Hirose et al.

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[54]	POLISHING APPARATUS INCLUDING
	TURNTABLE WITH POLISHING SURFACE
	OF DIFFERENT HEIGHTS

[75] Inventors. Masayoshi Hirose, Yokohama; Yoshimi Sasaki, Atsugi, Akira Ogata; Seiji Ishikawa, both of Yokohama; Tamami Takahashi, Yamato; Hirokuni Hiyama, Tokyo; Yutaka Wada, Yokohama, all of Japan

[73] Assignee: Ebara Corporation, Tokyo, Japan

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[30] Foreign Application Priority Data

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[52]	U.S. Cl.			. <b>451/287</b> ; 451/288;	451/495,

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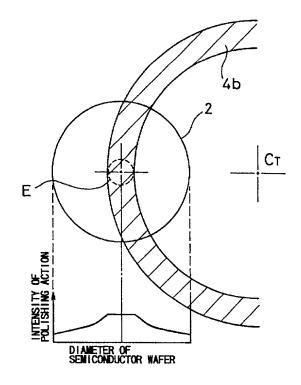
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## [57] ABSTRACT

A polishing apparatus includes a turntable with an abrasive cloth mounted on an upper surface thereof, and a top ring disposed above the turntable for supporting a workpiece to be polished and pressing the workpiece against the abrasive cloth under a predetermined pressure. The turntable and the top ring are movable relatively to each other to polish a surface of the workpiece supported by the top ring with the abrasive cloth. The abrasive cloth has a projecting region on a surface thereof for more intensive contact with the workpiece than other surface regions of the abrasive cloth. The projecting region has a smaller dimension in a radial direction of the turntable than a diameter of the workpiece when the projecting region is held in contact with the workpiece. A position of the projecting region is determined on the basis of an area in which the projecting region acts on the workpiece.

## 21 Claims, 21 Drawing Sheets



528, 530